

09/831722

JCU8 Rec'd PCT/PTO 14 MAY 2001

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

INFORMATION DISCLOSURE STATEMENT		Docket Number 10191/1728	
Application Number To Be Assigned	Filing Date Herewith	Examiner To Be Assigned	Art Unit To Be Assigned
Title DEVICE AND METHOD FOR PRODUCING A LOCAL PLASMA THROUGH MICROSTRUCTURE ELECTRODE DISCHARGES USING MICROWAVES		Applicant(s) Stefan GROSSE et al.	

Address to:
Assistant Commissioner
for Patents
Washington, D.C. 20231

1. In accordance with the duty of disclosure under 37 C.F.R. § 1.56 and in conformance with the procedures of 37 C.F.R. §§ 1.97 and 1.98 and M.P.E.P. § 609, attorneys for Applicant(s) hereby bring the following reference(s) to the attention of the Examiner. The reference(s) are listed on the attached modified PTO Form No. 1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.
2. A copy of each patent, publication or other information listed on the modified PTO form 1449 is enclosed, except as otherwise indicated on the modified PTO form 1449.

Dated: 5/14/01

By: *Richard L. Mayer*

Richard L. Mayer (Reg. No. 22,490)

KENYON & KENYON
One Broadway
New York, N.Y. 10004
(212) 425-7200 (telephone)
(212) 425-5288 (facsimile)

2L302704116

INFORMATION DISCLOSURE STATEMENT BY APPLICANT PTO FORM 1449	ATTY. DOCKET NO. 10191/1728	SERIAL NO. Not yet assigned
	APPLICANT(s) Stefan GROSSE et al.	
	FILING DATE Herewith	GROUP Not yet assigned

U. S. PATENT DOCUMENTS

EXAMINER INITIAL	PATENT NUMBER	PATENT DATE	NAME	CLASS	SUBCLASS	FILING DATE

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB- CLASS	TRANSLATION	
						YES	NO

OTHER DOCUMENTS

EXAMINER INITIAL		AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
		Frame et al., "Microdischarge Devices Fabricated in Silicon", Applied Physics Letters, US, American Institute of Physics, New York, Vol. 71, No. 9, 1 Sept. 1997, pp. 1165-1167*
		Ghanasev et al., "Surface Wave Eigenmodes in a Finite-Area Plane Microwave Plasma", Japanese Journal of Applied Physics, JP, Publication Office Japanese Journal of Applied Physics, Tokyo, Vol. 36, Part 1, No. 1A, 1997, pp. 337-344*
		Patent Abstracts of Japan, Vol. 1999, No. 05, 31 May 1999 & JP 11 045876 (Hitachi Ltd.), 16 February 1999*
		M. Roth et al., "Micro-Structure Electrodes as Electronic Interface Between Solid and Gas Phase: Electrically Steerable Catalysts for Chemical Reaction in the Gas Phase", 1997, 1st Int. Conf. on Microreaction Technology, Frankfurt/Main
		Kummer, "Grundlagen der Mikrowellentechnik" (Fundamentals of Microwave Technology), VEB Publishers-Technology, Berlin, 1986**

* Copy of reference is not enclosed because reference is cited and described in Search Report (copy of reference provided by International Searching Authority).

** Described in the Specification.

EXAMINER	DATE CONSIDERED
EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	